## D-3 Functional Thin Films

## **Representative Organizer**

Yasushi INOUE (Chiba Institute of Technology)

## <u>Co-organizers</u>

Yuichi SETSUHARA (Osaka University)

Kazuki YOSHIMURA (National Institute of Advanced Industrial Science and Technology)

Takashi KIMURA (Nagoya Institute of Technology)

Takeo NAKANO (Seikei University)

Poster Session	March 27 (Fri.)	$16:45 \sim 18:00$
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16:45	D3-P-01	Effects of Sputtering Mode on the Microstructure and Ionic Conductivity of Yttria-Stabilized Zirconia Films
		<sup>1</sup> Tsung-Her Yeh, <sup>2</sup> Ruei-De Lin, <sup>2</sup> Bo-Ruei Cherng, <sup>1,2</sup> Jyh-Shiarn Cherng
		1 CENTER FOR THIN FILM TECHNOLOGIES AND APPLICATIONS, MING CHI UNIVERSITY OF TECHNOLOGY 2 DEPARTMENT OF MATERIALS ENGINEERING, MING CHI UNIVERSITY OF TECHNOLOGY
16:45	D3-P-02	Behavior of SiO:CH Microparticles Synthesized by CCP-CVD Process <sup>1</sup> Haruka Koike, <sup>1</sup> Kouki Kosuge, <sup>1</sup> Naoki Goto, <sup>1</sup> Yasushi Inoue, <sup>2</sup> Osamu Takai
		I DEPARTMENT OF MECHANICAL SCIENCE AND ENGINEERING, CHIBA INSTITUTE OF TECHNOLOGY 2 MTERIAL AND SURFACE ENGINEERING RESEARCH INSTITUTE, KANTO GAKUIN UNIVERSITY
16:45	D3-P-03	Formation of Hybrid Hafnium Oxide Using Silicon Source
		<u>Chiung-Wei Lin</u> , Bo-Sheng Zheng, Jing-Wei Huang DEPARTMENT OF ELECTRICAL ENGINEERING, TATUNG UNIVERSITY
16:45	D3-P-04	Low-Temperature Growth of Zincblende-Type Crystal Phase of Tin-Nitride Films by Glancing-Angle Reactive Sputtering
		<sup>1</sup> Yasushi Inoue, <sup>1</sup> Fuminori Watanabe, <sup>2</sup> Osamu Takai
		I DEPARTMENT OF MECHANICAL SCIENCE AND ENGINEERING, CHIBA INSTITUTE OF TECHNOLOGY 2 MTERIAL AND SURFACE ENGINEERING RESEARCH INSTITUTE, KANTO GAKUIN UNIVERSITY
16:45	D3-P-05	Pressure Sensitivity of Amorphous Carbon Nitride Films in Gas Flow Measurement Naoyuki Tamura, Masami Aono, Tomo Harata, Nobuaki Kitazawa, Yoshihisa Watanabe
		DEPARTMENT OF MATERIALS SCIENCE AND ENGINEERING, NATIONAL DEFENSE ACADEMY
16:45	D3-P-06	Low Resistivity Copper Doped p-Type Cobalt Oxide Thin Films by Reactive Ion Beam Sputter Deposition
		Jun-Ron Li, Liang-Chiun Chao
		DEPARTMENT OF ELECTRONIC AND COMPUTER ENGINEERING, NATIONAL TAIWAN UNIVERSITY OF SCIENCE AND TECHNOLOGY
16:45	D3-P-07	A Simple Simulation for Fabrication of Isolated-Nanocolumnar Structures in Glancing-Angle Reactive Evaporation Process
		<sup>1</sup> <u>Akihiro Nakao</u> , <sup>1</sup> Takashige Masukawa, <sup>1</sup> Yasushi Inoue, <sup>2</sup> Osamu Takai
		I DEPARTMENT OF MECHANICAL SCIENCE AND ENGINEERING, CHIBA INSTITUTE OF TECHNOLOGY 2 MTERIAL AND SURFACE ENGINEERING RESEARCH INSTITUTE, KANTO GAKUIN UNIVERSITY
16:45	D3-P-08	Separation of the Semi- and Metal- Single Wall Carbon Nanotube by Surfactant and DNA with Electrophoresis Method
		<sup>1</sup> <u>Hsi-Chao Chen</u> , <sup>2</sup> Chih-Feng Yen, <sup>1</sup> Hsin-Ta Lee, <sup>1</sup> Guan-Jhen Chen, <sup>2</sup> Tzu-Ti Hsiaod, <sup>1</sup> Wan-Ting Yang
		1 DEPARTMENT OF ELECTRONIC ENGINEERING, NATIONAL YUNLIN UNIVERSITY OF SCIENCE AND TECHNOLOGY 2 DEPARTMENT OF OBSTETRICS AND GYNECOLOGY, LINKOU CHUNG GUNG MEMORIAL HOSPITAL

16:45	D3-P-09	Preparation and Characterization of Aldehyde and Epoxide Functionalized Surface by Plasma Polymerization
		<sup>1</sup> <u>Su-Yeong Kim</u> , <sup>1</sup> Yeong-Mu Ko, <sup>1</sup> Byung-Hoon Kim, <sup>2</sup> Min-Suk Kook 1 DEPARTMENT OF DENTAL MATERIALS, MRC, CHOSUN UNIVERSITY 2 DEPARTMENT OF ORAL & MAXILLOFACIAL SURGERY, SCHOOL OF DENTISTRY, CHONNAM NATIONAL UNIVERSITY
16:45	D3-P-10	Adsorption-Induced Electrochromic Properties of Microvillus-Structured InN Films in Nonaqueous Solutions
		<sup>1</sup> <u>Takashige Masukawa</u> , <sup>1</sup> Yasushi Inoue, <sup>2</sup> Osamu Takai 1 DEPARTMENT OF MECHANICAL SCIENCE AND ENGINEERING, CHIBA INSTITUTE OF TECHNOLOGY 2 MATERIAL AND SURFACE ENGINEERING RESEARCH INSTITUTE, KANTO GAKUIN UNIVERSITY
16:45	D3-P-11	<b>Optical, Electrochemical and Opto-Electrochemical Properties of Tunable TaOxNy Thin Films</b> <sup>1,2</sup> Jang-Hsing Hsieh, <sup>1,2</sup> <u>Yi-Chih Lin</u> , <sup>1,2</sup> Yi-Hua Lai
		I DEPARTMENT OF MATERIALS ENGINEERING, MING CHI UNIVERSITY OF TECHNOLOGY 2 CENTER FOR THIN FILMS TECHNOLOGIES AND APPLICATIONS, MING CHI UNIVERSITY OF TECHNOLOGY
16:45	D3-P-12	Preparation of Ti and TiN Flms Using Bipolar-Type Plasma Based Ion Implantation Combined with Sputtering
		<sup>1</sup> <u>Setsuo Nakao</u> , <sup>1</sup> Tsutomu Sonoda, <sup>1</sup> Takeshi Kusumori, <sup>1</sup> Kimihiro Ozaki, <sup>2</sup> Kingo Azuma, <sup>3</sup> Takashi Kimura 1 GREIMM, AIST-CHUBU 2 HYOGO UNIVERSITY OF TECHNOLOGY 3 NAGOYA INSTITUTE OF TECHNOLOGY
16:45	D3-P-13	Effect of Hydrogen-Containing Amorphous Carbon Films-Coated Titanium on Osteoblast and Osteoclast Differentiation <i>in vitro</i>
		<sup>1</sup> <u>Tatsuyuki Nakatani</u> , <sup>2</sup> Yuichi Mine, <sup>2</sup> Kentaro Takagi, <sup>3</sup> Shintarou Hara, <sup>3</sup> Keishi Okamoto, <sup>2</sup> Sumiyo Mimura, <sup>2</sup> Hiroki Nikawa
		I RESEARCH INSTITUTE OF TECHNOLOGY, OKAYAMA UNIVERSITY OF SCIENCE 2 DEPARTMENT OF ORAL BIOLOGY & ENGINEERING, INTEGRATED HEALTH SCIENCES, INSTITUTE OF BIOMEDICAL AND HEALTH SCIENCES, HIROSHIMA UNIVERSITY 2 TOYO ADVANCED TECHNOLOGIES CO., LTD.
16:45	D3-P-14	Dependence of Out-of-Plane Insulator-Metal Transition Characteristics of VO <sub>2</sub> Films on Bottom Electrode in Layered Structure Device
		Md.Suruz Mian, Kunio Okimura
		GRADUATE SCHOOL OF SCIENCE AND TECHNOLOGY, TOKAI UNIVERSITY
16:45	D3-P-15	<b>Deposition of Super-Hard Titanium Carbide Thin Films by Cathodic Vacuum Arc Plasma</b> <sup>1</sup> <u>Shintarou Hara</u> , <sup>1</sup> Keishi Okamoto, <sup>2</sup> Tatsuyuki Nakatani
		I TOYO ADVANCED TECHNOLOGIES CO.,LTD. 2 RESEARCH INSTITUTE OF TECHNOLOGY, OKAYAMA UNIVERSITY OF SCIENCE
16:45	D3-P-16	Preparation of DLC Films by High Power Pulsed Magnetron Sputtering with Bipolar Pulsed Voltage Source
		<sup>1</sup> <u>Taku Suyama</u> , <sup>1,2</sup> Takashi Kimura, <sup>3</sup> Setsuo Nakao, <sup>3</sup> Tsutomu Sonoda, <sup>3</sup> Takeshi Kusumori, <sup>3</sup> Kimihiro Ozaki, <sup>4</sup> Kingo Azuma
		I DEPARTMENT OF MECHANICAL ENGINEERING, NAGOYA INSTITUTE OF TECHNOLOGY 2 DEPARTMENT OF ENGINEERING PHYSICS, NAGOYA INSTITUTE OF TECHNOLOGY 3 NATIONAL INSTITUTE OF ADVANCED INDUSTRIAL SCIENCE AND TECHNOLOGY, CHUBU-CENTER 4 DEPARTMENT OF ELECTRICAL ENGINEERING AND COMPUTER SCIENCES, UNIVERSITY OF HYOGO
16:45	D3-P-17	Preparation of DLC Films by High Power Pulsed Magnetron Sputtering with Facing Targets
		<sup>1</sup> <u>Toshihiko Mishima</u> , <sup>1,2</sup> Takashi Kimura, <sup>3</sup> Kingo Azuma, <sup>4</sup> Setsuo Nakao
		I DEPARTMENT OF MECHANICAL ENGINEERING, NAGOYA INSTITUTE OF TECHNOLOGY 2 DEPARTMENT OF ENGINEERING PHYSICS, NAGOYA INSTITUTE OF TECHNOLOGY
		3 DEPARTMENT OF ELECTRICAL ENGINEERING AND COMPUTER SCIENCES, UNIVERSITY OF HYOGO 4 NATIONAL INSTITUTE OF ADVANCED INDUSTRIAL SCIENCE AND TECHNOLOGY, CHUBU-CENTER

16:45	D3-P-19	Deposition of Hydrogen-Containing Tetrahedral Amorphous Carbon Films by Cathodic Vacuum Arc Method
		<sup>1</sup> Koutarou Shiraishi, <sup>2</sup> Tatsuyuki Nakatani, <sup>3</sup> <u>Shinsuke Kunitsugu</u> 1 DEPARTMENT OF MECHANICAL SYSTEMS ENGINEERING, OKAYAMA UNIVERSITY OF SCIENCE 2 RESEARCH INSTITUTE OF TECHNOLOGY, OKAYAMA UNIVERSITY OF SCIENCE
		3 INDUSTRIAL TECHNOLOGY CENTER OF OKAYAMA PREFECTURE
16:45	D3-P-20	Vacuum Depositon of Sodium Chloride for Using as a Sacrifice Layer <sup>1</sup> Yu Miyamoto, <sup>1</sup> Yuma Fujii, <sup>1</sup> Yoshiyuki Suda, <sup>1</sup> Hirofumi Takikawa, <sup>2</sup> Hideto Tanoue, <sup>3</sup> Mamiko Nishiuchi, <sup>3</sup> Hironao Sasaki, <sup>3</sup> Kiminori Kondo
		I DEPT. OF ELECTRICAL & ELECTRONIC INFORMATION ENGINEERING, TOYOHASHI UNIVERSITY OF TECHNOLOGY 2 DEPT. OF ELECTRICAL & ELECTRONIC ENGINEERING, KITAKYUSHU NATIONAL COLLEGE OF TECHNOLOGY 3 JAPAN ATOMIC ENERGY AGENCY
16:45	D3-P-21	Enhancing the Current Efficiency and Color Stability of White Phosphorescent Organic Light-Emitting Diodes Using a Charge Control Layer
		Bi-Yu Huang, Shui-Hsiang Su, Yu-Cheng Lin, Meiso Yokoyama
		DEPARTMENT OF ELECTRONIC ENGINEERING I-SHOU UNIVERSITY
16:45	D3-P-22	Deposition of Zinc Oxide Films with Atomospheric-Pressure Plasma-Assisted Mist CVD Kosuke Takenaka, Giichiro Uchida, Yuichi Setsuhara
		JOINING AND WELDING RESEARCH INSTITUTE, OSAKA UNIVERSITY
16:45	D3-P-23	Low Temperature Synthesis of Carbon Nitride Using Microwave Plasma CVD <sup>1</sup> Ippei Tanaka, <sup>2</sup> Yukihiro Sakamoto
		1 GRADUATE SCHOOL, CHIBA INSTITUTE OF TECHNOLOGY 2 CHIBA INSTITUTE OF TECHNOLOGY
16:45	D3-P-24	Simultaneous Determination of N-acetyl- <i>p</i> -aminophenol and <i>p</i> -aminophenol with Poly(2,2' -(1,4-phenylenedivinylene) bis-8-hydroxyquinoline) Modified Glassy Carbon Electrode
		<u>Hayati Filik</u> , Sevda Aydar, Asiye Aslihan Avan
		ISTANBUL UNIVERSITY, FACULTY OF ENGINEERING, DEPARTMENT OF CHEMISTRY
16:45	D3-P-25	The Effect of CO <sub>2</sub> Gas for Calcareous Deposit Films Formation and Their Structure in Seawater Jae-Wook Kang, Jun-Mu Park, Jun Kang, Yong-Sup Yun, Myeong-Hoon Lee
		DIVISION OF MARINE ENGINEERING, KOREA MARITIME AND OCEAN UNIVERSITY
16:45	D3-P-26	Corrosion Behaviour of Al-Mg Coated Steel Sheet with Different Mg Content Prepared by PVD Method
		Jae-Wook Kang, Jun-Mu Park, Yong-Sup Yun, Jun Kang, Myeong-Hoon Lee
		DIVISION OF MARINE ENGINEERING, KOREA MARITIME AND OCEAN UNIVERSITY
16:45	D3-P-27	Effect of Heat Treatment on Corrosion Resistance of Magnesium Alloy Coatings on Electrogalvanized Steel
		Jae-Wook Kang, Yeon Won Kim, Jun-Mu Park, Sung Hwa-Hwang, Jun Kang, Myeong-Hoon Lee DIVISION OF MARINE ENGINEERING, KOREA MARITIME AND OCEAN UNIVERSITY
16:45	D3-P-28	Effects of H <sub>2</sub> O Plasma Treatment for Copper Electroplating on B-Doped Diamond Substrates. <sup>1</sup> Shuji Tamamura, <sup>2</sup> Yukihiro Sakamoto
		I GRADUATE SCHOOL, CHIBA INSTITUTE OF TECHNOLOGY 2 CHIBA INSTITUTE OF TECHNOLOGY
16:45	D3-P-29	Effect of Thermal Theatments and pH Values on Electrical and Physical Properties of NdAlO <sub>3</sub> Dielectric Thin Films Using Sol-Gel Method
		Ching-Fang Tseng, Po-An Lin, Tzu-Chun Wei
		DEDADTMENT OF ELECTRONIC ENCINEEDING, NATIONAL UNITED UNIVERSITY

DEPARTMENT OF ELECTRONIC ENGINEERING, NATIONAL UNITED UNIVERSITY

16:45	D3-P-30	<b>Preparation of Three-Dimensional Structure CVD Diamond by Control of the Nucleation</b> <b>Site by Using Silicon Oxide Film</b> <sup>1</sup> <u>Takahiro Hattori</u> , <sup>2</sup> Yukihiro Sakamoto
		1 GRADUATE SCHOOL, CHIBA INSTITUTE OF TECHNOLOGY 2 FACULTY OF ENGINEERING, CHIBA INSTITUTE OF TECHNOLOGY
16:45	D3-P-31	<b>Electrical Properties of Mg<sub>x</sub>Zn<sub>1-x</sub> O Thin Films Deposited by RF Co-Sputtering</b> <sup>1</sup> Li Li Yue, <sup>1</sup> Hong Seung Kim, <sup>2</sup> Nak Won Jang
		I DEPARTMENT OF NANO SEMICONDUCTOR ENGINEERING, KOREA MARITIME AND OCEAN UNIVERSITY 2 DIVISION OF ELECTRICAL AND ELECTRONICS ENGINEERING, KOREA MARITIME AND OCEAN UNIVERSITY
16:45	D3-P-32	Enhancing the Photocurrent of Organic Phototransistor by Using Sol-Gel Dielectric Layers <u>Jin-Yi Huang</u> , Shui-Hsiang Su, Shang-Hsuan Li, Yu-Jun Lin, Meiso Yokoyama DEPARTMENT OF ELECTRONIC ENGINEERING I-SHOU UNIVERSITY
16:45	D3-P-33	Titanium Nitride Deposition by High Power Pulsed Sputtering Penning Discharge under the Argin/Nitrogen Mixture Gases
		Kingo Azuma, <u>Yuhma Kusuhashi</u> , Kazuma Edagawa, Shinichi Honda DEPARTMENT OF ELECTRICAL ENGINEERING AND COMPUTER SCIENCES, UNIVERSITY OF HYOGO
16:45	D3-P-34	Effect of Mg Contents on the Corrosion Properties of the Zn-Mg Coatings Joung Hyun La, Ki Tae Bae, Sang Yul Lee
		CENTER FOR SURFACE TECHNOLOGY AND APPLICATIONS, DEPARTMENT OF MATERIALS ENGINEERING, KOREA AEROSPACE UNIVERSITY
16:45	D3-P-35	Vacuum Ultraviolet Light Induced Chemical Modification of Cyclo-Olefin Polymer Surface Dependent of the Irradiation Atmosphere
		<sup>1</sup> Young-Jong Kim, <sup>2</sup> Hiroyuki Sugimura, <sup>3</sup> Jun Kang, <sup>3</sup> Myeong-Hoon Lee
		1 PRODUCTION ENGINEERING RESEARCH INSTITUTE, LG ELECTRONICS 2 DEPARTMENT OF MATERIALS SCIENCE AND ENGINEERING, KYOTO UNIVERSITY 3 DIVISION OF MARINE ENGINEERING, KOREA MARITIME AND OCEAN UNIVERSITY
16:45	D3-P-36	Photochemical Activation of Cyclo-Olefin Polymer Surfaces for Improved Adhesion <sup>1</sup> Young-Jong Kim, <sup>2</sup> Hiroyuki Sugimura, <sup>3</sup> Jun Kang, <sup>3</sup> Myeong-Hoon Lee
		I PRODUCTION ENGINEERING RESEARCH INSTITUTE, LG ELECTRONICS 2 DEPARTMENT OF MATERIALS SCIENCE AND ENGINEERING, KYOTO UNIVERSITY 3 DIVISION OF MARINE ENGINEERING, KOREA MARITIME AND OCEAN UNIVERSITY
16:45	D3-P-37	<b>Organosilane Multilayers Formation by Photochemical Surface Modification</b> <sup>1</sup> Young-Jong Kim, <sup>2</sup> Hiroyuki Sugimura, <sup>3</sup> Jun Kang, <sup>3</sup> Myeong-Hoon Lee
		I PRODUCTION ENGINEERING RESEARCH INSTITUTE, LG ELECTRONICS 2 DEPARTMENT OF MATERIALS SCIENCE AND ENGINEERING, KYOTO UNIVERSITY 3 DIVISION OF MARINE ENGINEERING, KOREA MARITIME AND OCEAN UNIVERSITY
16:45	D3-P-38	<b>Development of Ni-W Alloy Plating as a Substitution of Hard Chromium</b> <sup>1,2</sup> Sojiro Kirihara, <sup>2</sup> Yasushi Umeda, <sup>2</sup> Katsuhiko Tashiro, <sup>2</sup> Hideo Honma, <sup>1,2</sup> Osamu Takai
		I DEPARTMENT OF INDUSTRIAL CHEMISTRY, GRADUATE SCHOOL OF ENGINEERING, KANTO GAKUIN UNIVERSITY 2 MATERIALS & SURFACE ENGINEERING RESEARCH INSTITUTE, KANTO GAKUIN UNIVERSITY
16:45	D3-P-39	Study on Crystallite Formed on Copper Foil in Aqueous Ammonia Akio Mochida, Kazunori Matsui
		DEPARTMENT OF MATERIAL AND LIFE SCIENCE, GRADUATE SCHOOL OF ENGINEERING, KANTO GAKUIN UNIVERSITY
16:45	D3-P-40	Formation of Alq <sub>3</sub> Film on Aluminum Surface Anodized and Treated in Boiling Water with the Reaction of 8-Hydroxyquinoline
		Shohei Yamaguchi, Kazunori Matsui GRADUATE SCHOOL OF ENGINEERING, KANTO GAKUIN UNIVERSITY

16:45	D3-P-41	<b>Fine Metal Pattern Formation on Transparency Resins by Wet Processing</b> <sup>1,2</sup> <u>Yoshio Horiuchi</u> , <sup>2</sup> Christopher E.J.Cordonier, <sup>2</sup> Joo-Hyong Noh, <sup>2</sup> Hideo Honma, <sup>1,2</sup> Osam Takai <i>1 DEPARTMENT OF INDUSTRIAL CHEMISTRY, GRADUATE SCHOOL OF ENGINEERING, KANTO GAKUIN UNIVERSITY</i> <i>2 MATERIALS &amp; SURFACE ENGINEERING RESEARCH INSTITUTE, KANTO GAKUIN UNIVERSITY</i>
16:45	D3-P-42	Atomic Layer Layer Deposition of TiN Based Coatings for Bipolar Plates Eun Young Yun, <u>Se Hun Kwon</u> SCHOOL OF MATERIALS SCIENCE AND ENGINEERING, PUSAN NATIONAL UNIVERSITY
16:45	D3-P-43	The Properties of TiAlVN Coating Synthesized by Magnetron Sputtering Process with Single Composite Target <sup>1,2</sup> <u>H.C.Lee</u> , <sup>1</sup> J.H.Pyun, <sup>2</sup> P.K.Shin, <sup>1</sup> K.I.Moon <i>1 KOREA INSTITUTE OF INDUSTRIAL TECHNOLOGY, HEAT &amp; SURFACE TECHNOLOGY SERVICE CENTER</i> <i>2 SCHOOLS OF ELECTRICAL ENGINEERING, INHA UNIVERSITY</i>
16:45	D3-P-44	A Study on the Ternary Elements Si Addition on the Mo-Cu Coating Deposited by Magnetron Sputtering Process with Single Alloying Target <sup>1,2</sup> <u>H.C.Lee</u> , <sup>1</sup> J.H.Pyun, <sup>2</sup> P.K.Shin, <sup>1</sup> K.I.Moon <i>1 KOREA INSTITUTE OF INDUSTRIAL TECHNOLOGY, HEAT &amp; SURFACE TECHNOLOGY SERVICE CENTER</i> <i>2 SCHOOLS OF ELECTRICAL ENGINEERING, INHA UNIVERSITY</i>
16:45	D3-P-45	Effect of Substrate Temperature on Properties of CaLa <sub>4</sub> (Zr <sub>0.05</sub> Ti <sub>0.95</sub> ) <sub>4</sub> O <sub>15</sub> Thin Films by RF Magnetron Sputtering <sup>1</sup> Cheng-Hsing Hsu, <sup>2</sup> Chun-Hung Lai, <sup>1</sup> Chia-Hsien Chang <i>1 DEPARTMENT OF ELECTRICAL ENGINEERING, NATIONAL UNITED UNIVERSITY</i> <i>2 DEPARTMENT OF ELECTRONIC ENGINEERING, NATIONAL UNITED UNIVERSITY</i>
16:45	D3-P-46	Effects of Nitrocarburizing Processing Times after Radical Nitriding for Surface Hardening of SKH51 <sup>1</sup> Yusuke Kikuchi, <sup>2</sup> Yukihiro Sakamoto <i>1 GRADUATE SCHOOL, CHIBA INSTITUTE OF TECHNOLOGY</i> <i>2 FACULTY OF ENGINIERING, CHIBA INSTITUTE OF TECHNOLOGY</i>
16:45	D3-P-47	<b>Electrical Properties of Mg<sub>x</sub>Zn<sub>1-x</sub> O Thin Films Deposited by RF Co-Sputtering</b> <sup>1</sup> Li Li Yue, <sup>1</sup> Hong Seung Kim, <sup>2</sup> Nak Won Jang <i>I DEPARTMENT OF NANO SEMICONDUCTOR ENGINEERING, KOREA MARITIME AND OCEAN UNIVERSITY</i> <i>2 DIVISION OF ELECTRICAL AND ELECTRONICS ENGINEERING, KOREA MARITIME AND OCEAN UNIVERSITY</i>
16:45	D3-P-48	Effects of the Sputtering Pressure on the Preparation of Titanium Iodized Films by Reactive Magnetron Sputtering <sup>1</sup> Kaori Fujimaki, <sup>2</sup> Yukihiro Sakamoto <i>1 GRADUATE SCHOOL, CHIBA INSTITUTE OF TECHNOLOGY</i> <i>2 CHIBA INSTITUTE OF TECHNOLOGY</i>
16:45	D3-P-49L	Reactive Sputter Deposition of Titanium Nitride on Silicon via a Magnetized Sheet Plasma Source Janella Salamania, Matthew Villanueva, Marcedon Fernandez, Henry Ramos PLASMA PHYSICS LABORATORY, NATIONAL INSTITUTE OF PHYSICS, UNIVERSITY OF THE PHILIPPINES